

<b>INFORMATION DISCLOSURE CITATION</b> (Use several sheets if necessary)	Docket Number (Optional) <b>S-101,670</b>	Application Number
	Applicant(s) <b>Jiangang Sun</b>	
	Filing Date	Group Art Unit

**U.S. PATENT DOCUMENTS**

EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
LOR	-	6,285,449	9/2/01	Ellingson, et al.			
LOR	-	5,689,332	11/18/97	Ellingson, et al.			

**FOREIGN PATENT DOCUMENTS**

REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						YES	NO

**OTHER DOCUMENTS** (Including Author, Title, Date, Pertinent Pages, Etc.)

LOR		H. R. Hee, et al. "Optical Coherence Tomography for Ophthalmic Imaging", IEEE Engineering in Medicine and Biology, 95
		Sun, et al., "Application of Optical Scattering Methods to Detect Damage in Ceramics", in Machining of Ceramics and Composites, Part IV; Chapter 19, edited by Jahanmir et al., in 1999, 1t 669.
LOR		Zhang et al., "SUBSURFACE DAMAGE MEASUREMENT IN SILICON WAFERS BY LASER SCATTERING", in Transactions of NAMS/SME, Vol. XXX, 2002, at 535.

EXAMINER <b>Luke Ruchle</b>	DATE CONSIDERED <b>8/29/05</b>
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EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.